

Patent  
Attorney's Docket No. 001425-108

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of )  
Ge XU et al. ) Group Art Unit: 1763  
Application No.: 09/863,338 ) Examiner: S. MacArthur  
Filed: May 24, 2001 ) Confirmation No.: 1018  
For: CVD APPARATUS ) VIA FACSIMILE

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MW

AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Official Action dated February 13, 2003, please amend the above-identified patent application as follows:

IN THE CLAIMS:

Please amend claims 1, 17, 23 and 24 as follows:

1. (Amended) A CVD apparatus comprising:

*Bl*  
a vacuum vessel having an inside in which plasma is produced to generate active species, and film deposition is performed on a substrate by using the active species and a reactive gas;

an electrically-conductive partitioning wall section formed in the vacuum vessel for separating the inside thereof into two chambers;